Fig.1

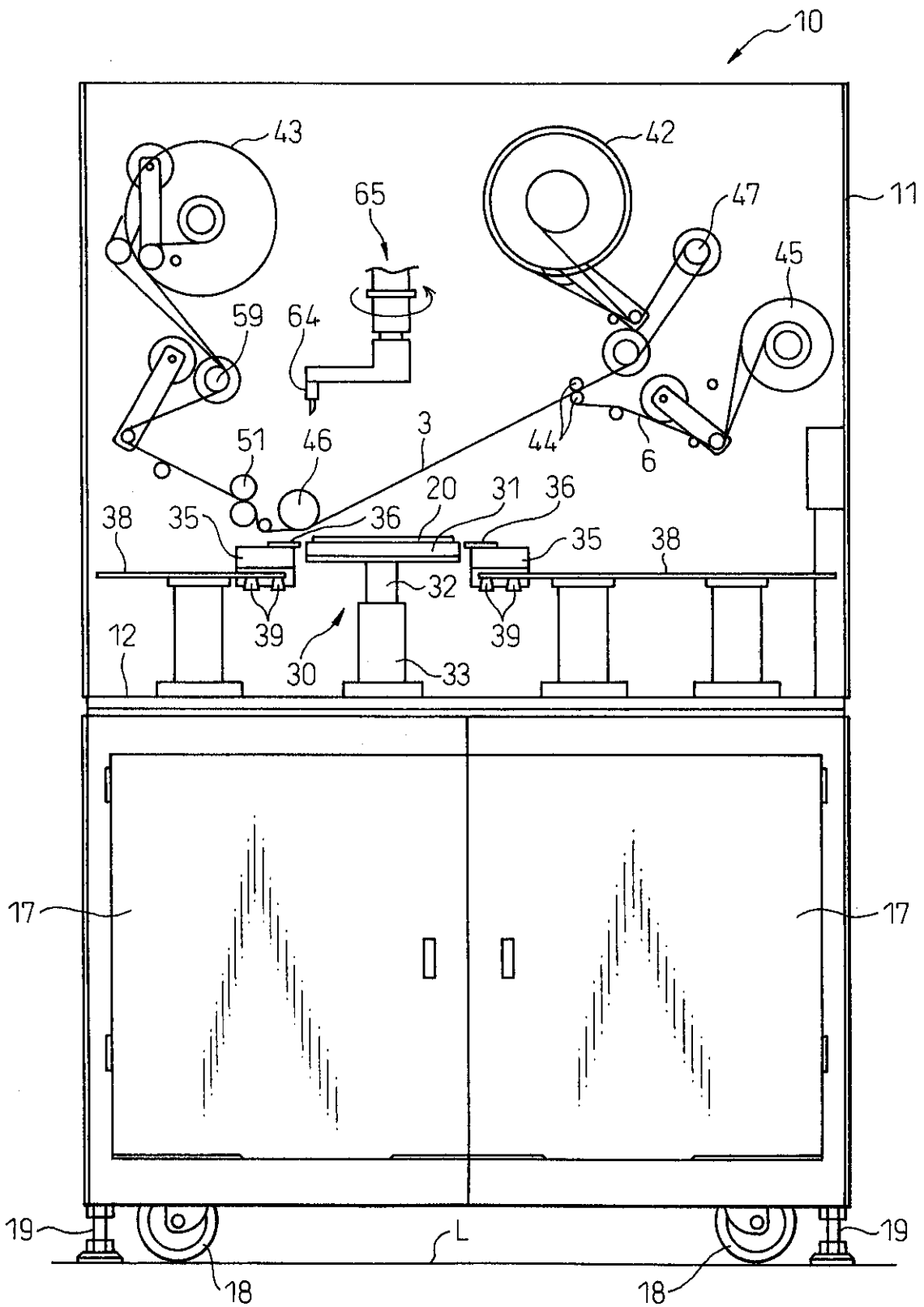

10
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Fig. 2

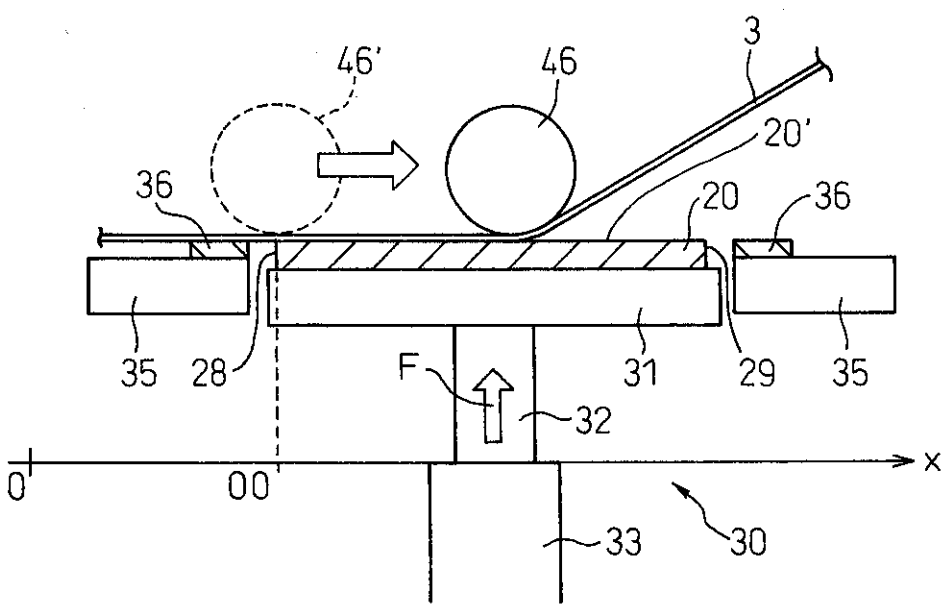


Fig.3

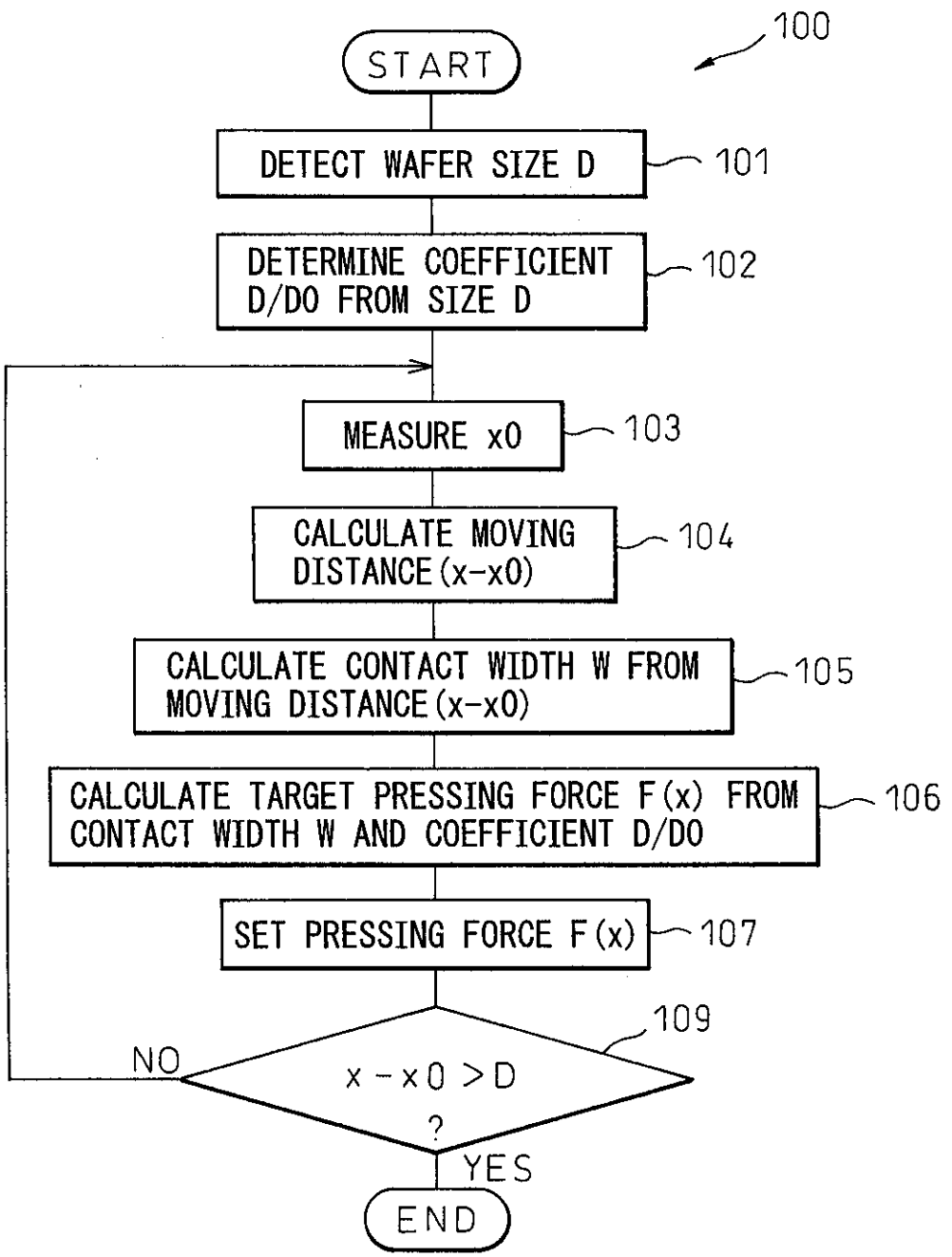

100
START
DETECT WAFER SIZE D
101
DETERMINE COEFFICIENT D/DO FROM SIZE D
102
MEASURE x0
103
CALCULATE MOVING DISTANCE (x-x0)
104
CALCULATE CONTACT WIDTH W FROM MOVING DISTANCE (x-x0)
105
CALCULATE TARGET PRESSING FORCE F(x) FROM CONTACT WIDTH W AND COEFFICIENT D/DO
106
SET PRESSING FORCE F(x)
107
109
x - x0 > D ?
NO
YES
END

Fig. 4

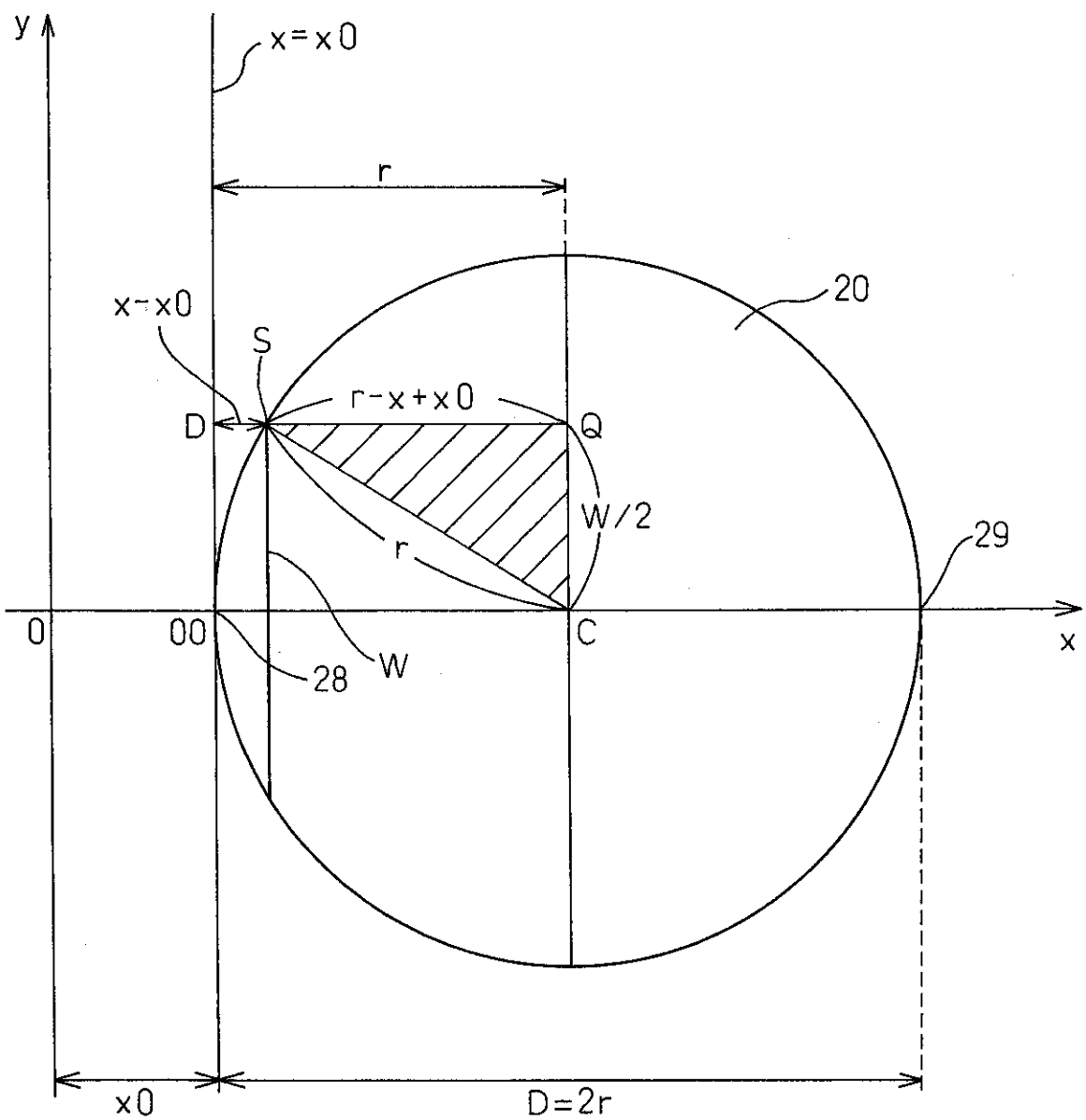


Fig.5a

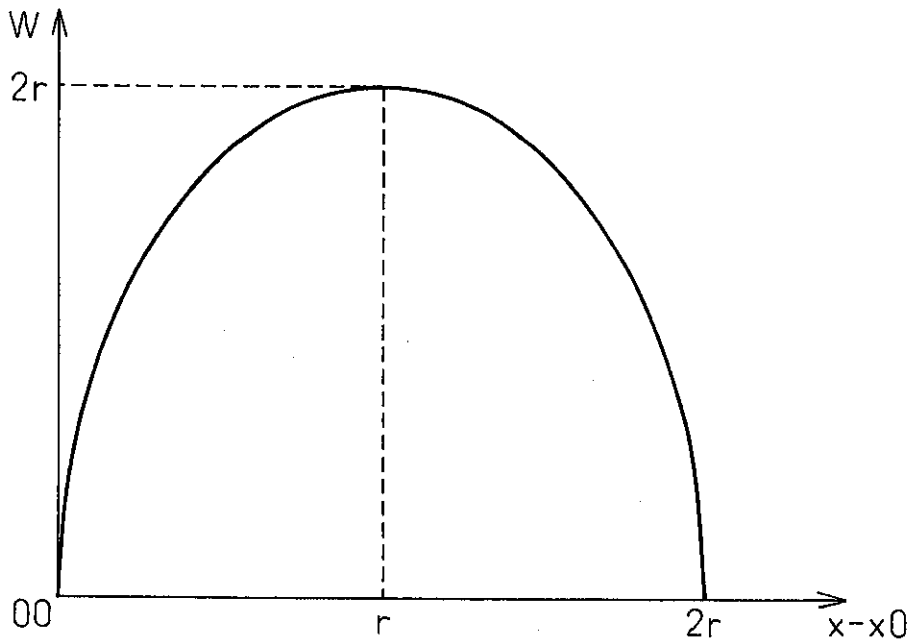


Fig.5b

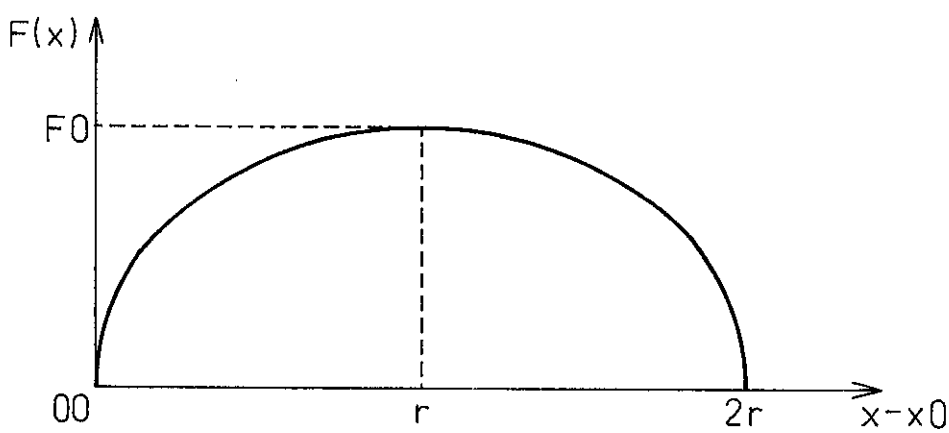


Fig.5c

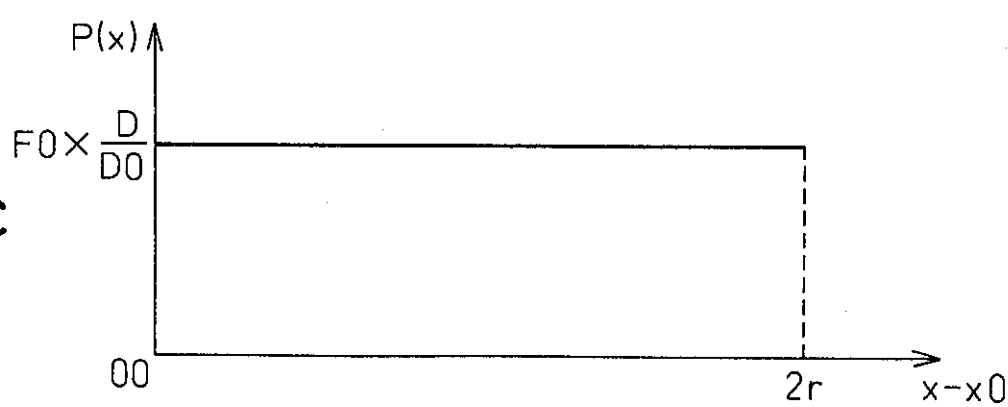


Fig.6

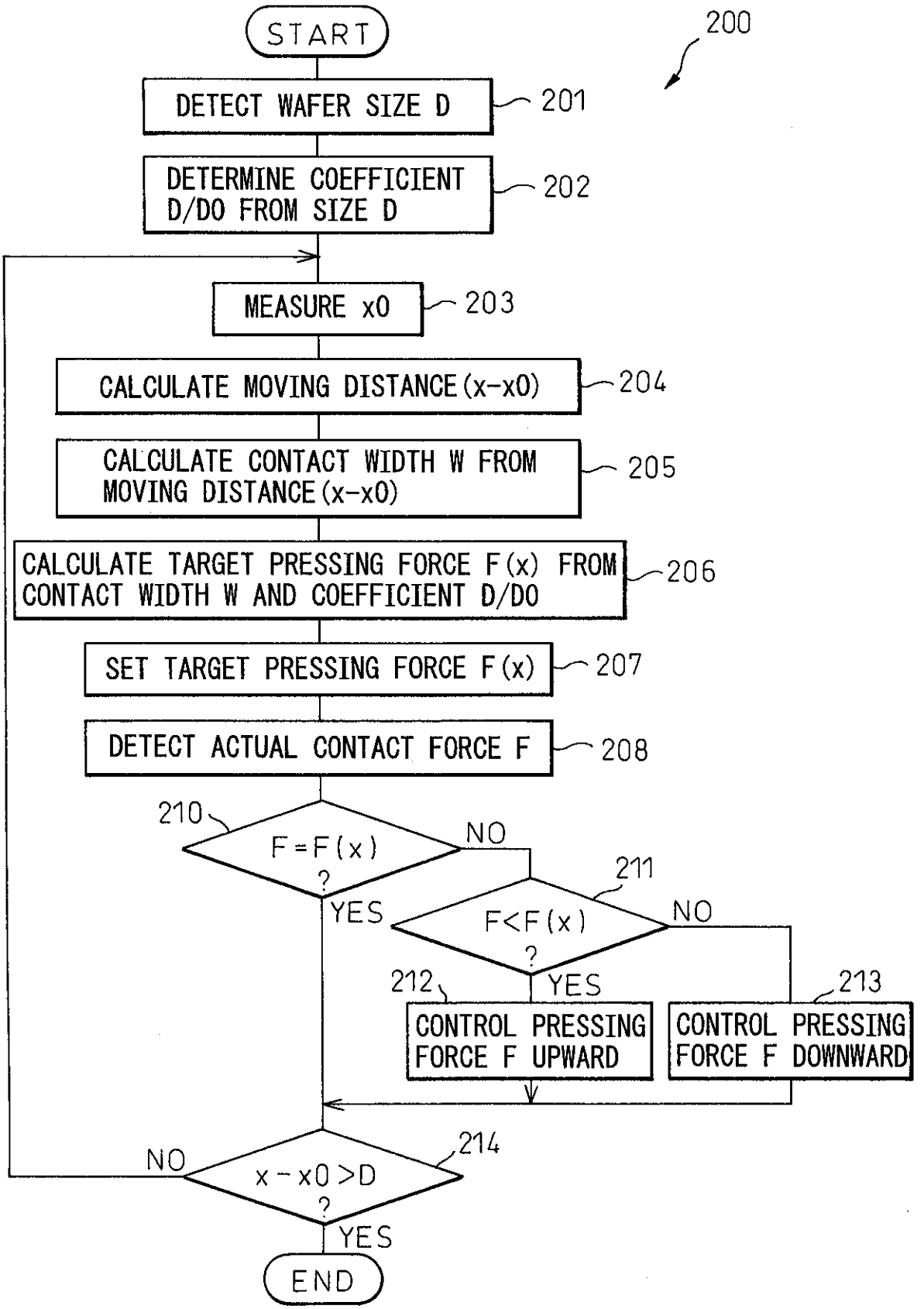

START
200
DETECT WAFER SIZE D
201
DETERMINE COEFFICIENT D/DO FROM SIZE D
202
MEASURE x0
203
CALCULATE MOVING DISTANCE (x-x0)
204
CALCULATE CONTACT WIDTH W FROM MOVING DISTANCE (x-x0)
205
CALCULATE TARGET PRESSING FORCE F(x) FROM CONTACT WIDTH W AND COEFFICIENT D/DO
206
SET TARGET PRESSING FORCE F(x)
207
DETECT ACTUAL CONTACT FORCE F
208
210
F=F(x) ?
NO
YES
211
F<F(x) ?
NO
YES
212
CONTROL PRESSING FORCE F UPWARD
213
CONTROL PRESSING FORCE F DOWNWARD
214
x-x0>D ?
NO
YES
END

Fig.7

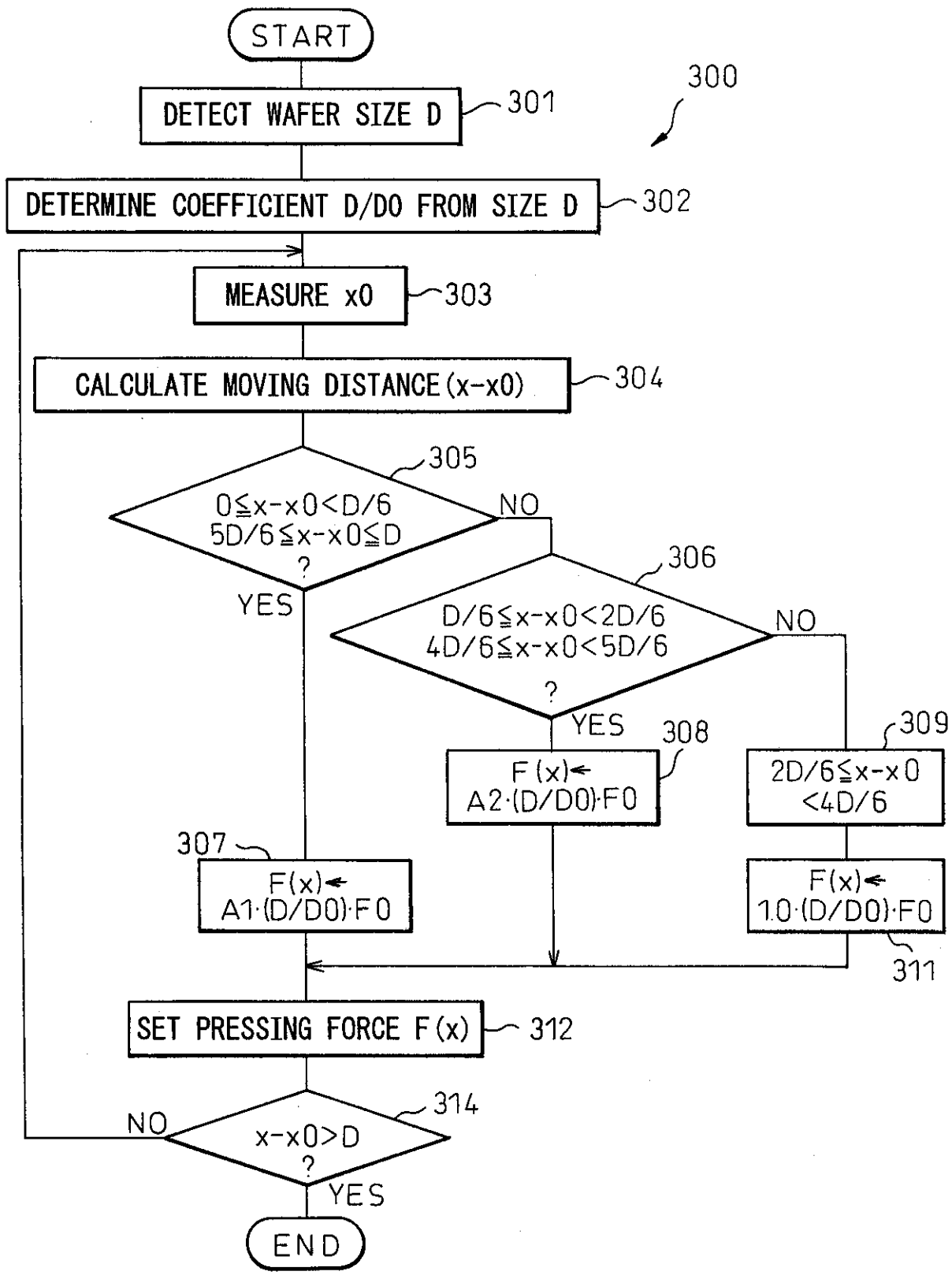

START
DETECT WAFER SIZE D
301
300
DETERMINE COEFFICIENT D/D0 FROM SIZE D
302
MEASURE x0
303
CALCULATE MOVING DISTANCE (x-x0)
304
305
0≦x-x0<D/6
5D/6≦x-x0≦D
?
NO
YES
306
D/6≦x-x0<2D/6
4D/6≦x-x0<5D/6
?
NO
YES
308
F(x)←
A2·(D/D0)·F0
309
2D/6≦x-x0
<4D/6
307
F(x)←
A1·(D/D0)·F0
F(x)←
1.0·(D/D0)·F0
311
SET PRESSING FORCE F(x)
312
314
NO
x-x0>D
?
YES
END

Fig.8a

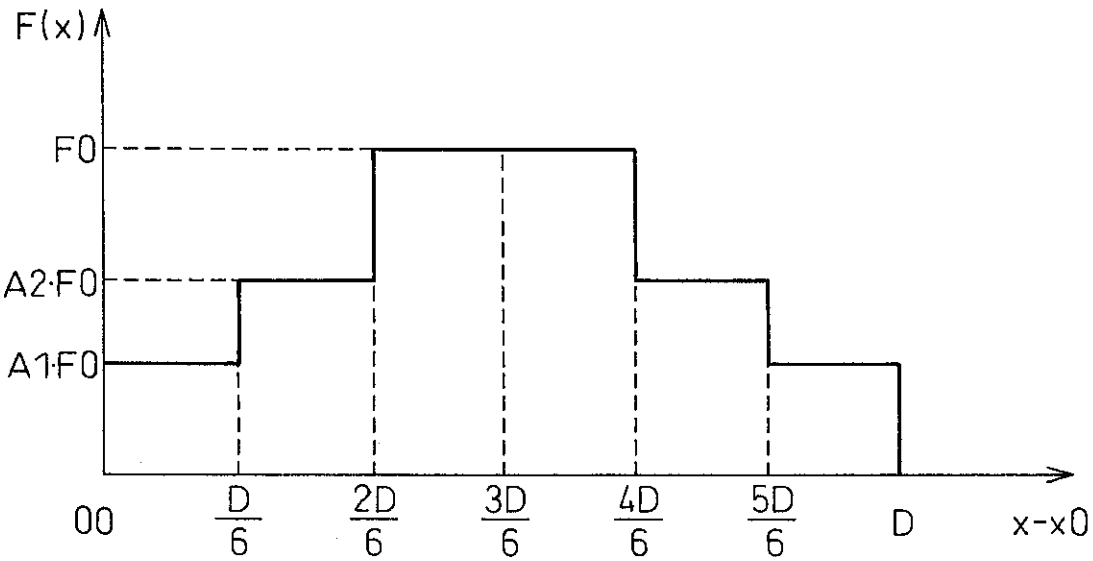

F(x)
F0
A2·F0
A1·F0
00
D/6
2D/6
3D/6
4D/6
5D/6
D
x-x0

Fig.8b

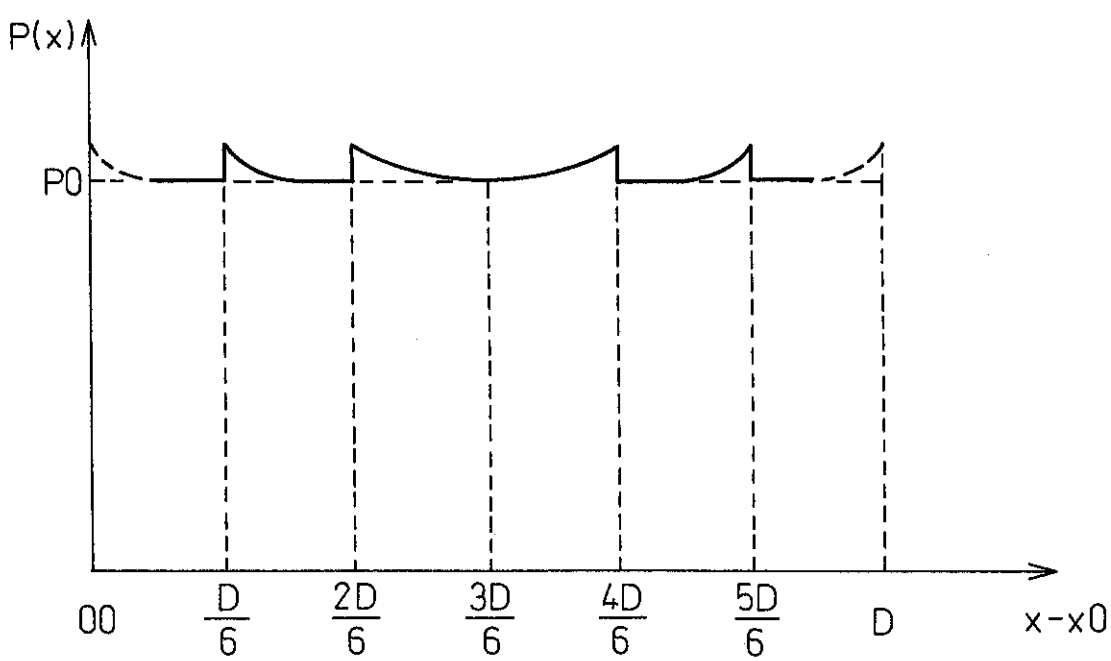

P(x)
P0
00
D/6
2D/6
3D/6
4D/6
5D/6
D
x-x0

Fig.9

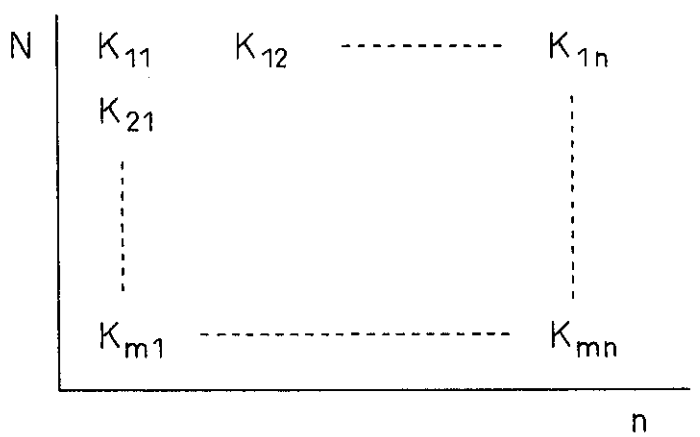


Fig.10a

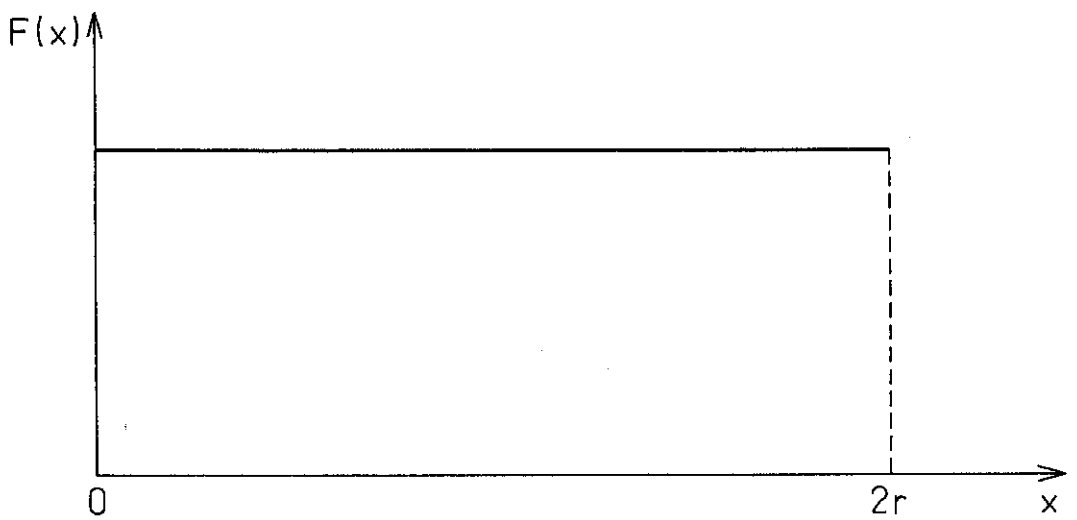


Fig.10b

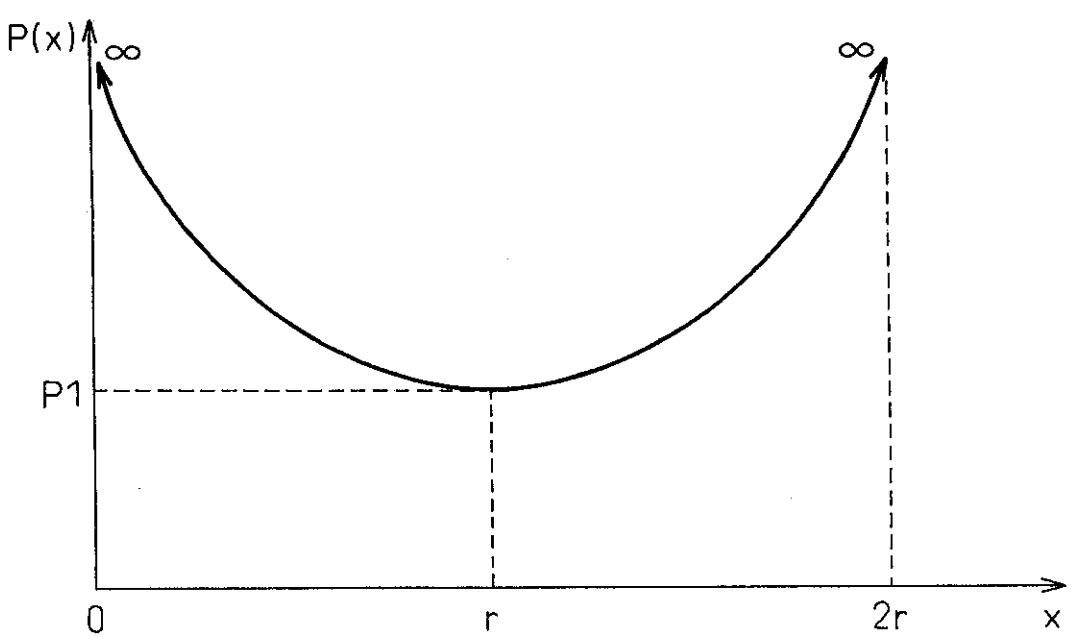


Fig.11a

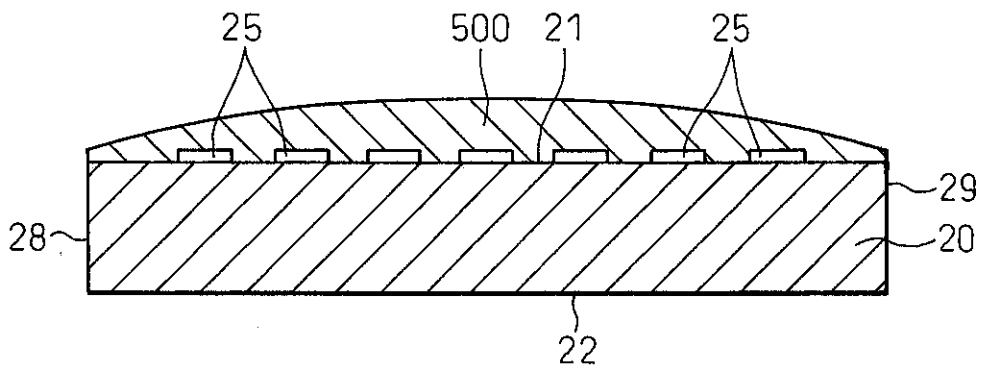


Fig.11b

